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# Emerging Digital Micromirror Device Based Systems and Applications X

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## Contents

- v Authors
- vii Conference Committee

SESSION 1	COMPUTATIONAL IMAGING FOR ADVANCED APPLICATIONS
10546 02	Where fewer pixels give you more image (Invited Paper) [10546-1]
10546 04	Single-pixel imaging using balanced detection and a digital micromirror device (Best Student Paper Award) [10546-3]
SESSION 2	ADVANCED MANUFACTURING USING DMD OR OTHER SLM: JOINT SESSION WITH CONFERENCES 10544 AND 10546
10546 06	Programmable CGH on photochromic material using DMD generated masks [10546-5]
SESSION 3	3D METROLOGY: JOINT SESSION WITH CONFERENCES 10544 AND 10546
10546 OA	Superfast 3D shape measurement of a flapping flight process with motion based segmentation [10546-8]
10546 OB	Universal phase unwrapping for phase measuring profilometry using geometry analysis [10546-9]
SESSION 4	BIOMEDICAL IMAGING WITH ADVANCED MICROSCOPY USING A DMD OR OTHER MEMS ARRAY
10546 OD	Use of digital micromirror devices as dynamic pinhole arrays for adaptive confocal fluorescence microscopy [10546-13]
10546 OE	DMD-based quantitative phase microscopy and optical diffraction tomography [10546-14]

## SESSION 5 BIOMEDICAL IMAGING USING A DMD OR OTHER LIGHT STRUCTURING DEVICES FOR OPHTHALMOLOGICAL APPLICATIONS

- 10546 0G Confocal retinal imaging using a digital light projector with a near infrared VCSEL source (Best Paper Award) [10546-16]
- 10546 01 Structured polarized light microscopy (SPLM) for mapping collagen fiber orientation of ocular tissues [10546-18]

#### SESSION 6 NOVEL AND ADVANCED APPLICATIONS

- 10546 0J Low intensity LiDAR using compressed sensing and a photon number resolving detector (Invited Paper) [10546-19]
- 10546 OK Headlamp innovations: optical concepts for fully adaptive light distributions [10546-20]
- 10546 OL DMDs for multi-object near-infrared spectrographs in astronomy [10546-21]

## **Authors**

Numbers in the index correspond to the last two digits of the seven-digit citation identifier (CID) article numbering system used in Proceedings of SPIE. The first five digits reflect the volume number. Base 36 numbering is employed for the last two digits and indicates the order of articles within the volume. Numbers start with 00, 01, 02, 03, 04, 05, 06, 07, 08, 09, 0A, 0B...0Z, followed by 10-1Z, 20-2Z, etc.

Alata, Romain, 06 Andrés, P., 04 Barkhouser, Robert, OL Bertarelli, Chiara, 06 Bianco, Andrea, 06 Brazile, Bryn, Ol Clemente, P., 04 Cohen, Lior, 0J Conley, Devin, 0L Edgar, Matthew, 02 Eisenberg, Hagai S., OJ Elsner, Ann E., 0G Gibson, Graham, 02 Gray, Aidan, OL Ho, Yo-Sung, OB Hope, Gavin, OL Hope, Stephen, OL Istrati, Daniel, OJ Jan, Ning-Jiun, Ol Kloppenburg, Gerolf, 0K Knöchelmann, Marvin, OK Lachmayer, Roland, OK Lancis, J., 04 Lanzoni, Patrick, 06 Lau, Daniel L., OB Li, Beiwen, OA Liu, Kai, OB Muller, Matthew S., 0G Padgett, Miles, 02 Pariani, Giorgio, 06 Pozzi, Paolo, OD Robberto, Massimo, OL Sher, Yoni, 0J Sigal, Ian A., Ol Smee, Stephen A., OL Soldevila, F., 04 Soloviev, Oleg, 0D Song, Jianwen, OB Tajahuerce, E., 04 Uribe-Patarroyo, Néstor, 04 Vdovin, Gleb, 0D Verhaegen, Michel, 0D Voorhees, Andrew P., Ol Wilding, Dean, 0D Yang, Bin, Ol Zamkotsian, Frédéric, 06 Zhou, Renjie, OE

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   Georg von Freymann, Technische Universität Kaiserslautern (Germany)
   Benjamin L. Lee, Texas Instruments Inc. (United States)
- 3 3D Metrology: Joint Session with Conferences 10544 and 10546
  Alex Lyubarsky, Texas Instruments Inc. (United States)
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- Biomedical Imaging with Advanced Microscopy using a DMD or other MEMS Array
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- Biomedical Imaging using a DMD or other Light Structuring Devices for Ophthalmological Applications
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   Robert C. Leif, Newport Instruments (United States)
- 6 Novel and Advanced Applications
  Alfred Jacobsen, Visitech Engineering GmbH (Germany)
  Benjamin L. Lee, Texas Instruments Inc. (United States)